

**EAST - [Piezoelectric element search.wsp:1]**

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☒ (8) (((("4782267") or ("4452642") or ("4626448") or ("5198070") or ("5282899") or ("5336533") or...  
☒ (5) 5336533.URPN.  
☒ (11) ("4113514" | "4224084" | "4532199" | "4609428" | "4818488" | "4891095" | "4898118" | "49522...  
☒ (4196) 315/111.18 315/111.01 204/192.12 250/423R  
☒ (60) (315/111.18 315/111.01 204/192.12 250/423R) and penn\$5 and magnetron  
☒ (51) (315/111.18 315/111.01 204/192.12 250/423R) and penn\$5 and cathode and ((315/111.18 315/111...  
☒ (4) (((("5300785") or ("6335534") or ("5378899") or ("5196706"))).PN.  
☒ (5183) scan\$ and pulse and (conductive near3 layer)  
☒ (250) (scan\$ and pulse and (conductive near3 layer)) and (secondary near3 electrons)  
☒ (184) ((scan\$ and pulse and (conductive near3 layer)) and (secondary near3 electrons)) and Insulat\$5  
☒ (170) (secondary near3 electron) and (scan near3 (count number))  
☒ (11) ((secondary near3 electron) and (scan near3 (count number))) and (contact near3 hole)  
☒ (3) ("5640539" | "6195773" | "6204075").PN.

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	U	I	Document ID	Issue Date	Pages	Title	Current OR	Current XRef	Retrieval Clas	
1	<input type="checkbox"/>	<input checked="" type="checkbox"/>	US 6001309 A	19991214	17	Jet droplet device	422/100	347/19; 347/85;		Gamb
2	<input type="checkbox"/>	<input checked="" type="checkbox"/>	US 6618850 B2	20030909	24	Inspection method and inspection system using charged particle bea	716/20	716/19; 716/21		Nishiy
3	<input type="checkbox"/>	<input checked="" type="checkbox"/>	US 6091249 A	20000718	22	Method and apparatus for detecting defects in wafers	324/751	324/750; 324/754;		Talbo et al.
4	<input type="checkbox"/>	<input checked="" type="checkbox"/>	US 5597459 A	19970128	15	Magnetron cathode sputtering method and apparatus	204/192.12	204/298.09; 204/298.11;		Altshu
5	<input type="checkbox"/>	<input checked="" type="checkbox"/>	US 5482611 A	19960109	16	Physical vapor deposition employing ion extraction from a pla	204/298.17	204/192.12; 204/298.05;		Helme
6	<input type="checkbox"/>	<input checked="" type="checkbox"/>	US 4842703 A	19890627	20	Magnetron cathode and method for sputter coating	204/192.12	204/298.18		Class.
7	<input type="checkbox"/>	<input checked="" type="checkbox"/>	US 4728862 A	19880301	6	A method for achieving ignition of a low voltage gas discharge device	315/111.01	313/161; 313/231.31;		Kovar
8	<input type="checkbox"/>	<input checked="" type="checkbox"/>	US 4423355 A	19831227	28	Ion generating apparatus	315/111.81	250/426; 313/231.41;		Kagey
9	<input type="checkbox"/>	<input checked="" type="checkbox"/>	US 6602425 B2	20030805	20	Method for low cost water disinfection	210/744	210/748; 250/430;		Gadgi
10	<input type="checkbox"/>	<input checked="" type="checkbox"/>	US 5628895 A	19970513	8	Closed circuit for treating drinking water with UV treatment and filter	210/85	210/143; 210/192;		Zuchc
11	<input type="checkbox"/>	<input checked="" type="checkbox"/>	US 5717204 A	19980210	36	Inspecting optical masks with electron beam microscopy	250/310	250/306; 250/307;		Melsb
12	<input type="checkbox"/>	<input checked="" type="checkbox"/>	US 4862414 A	19890829	25	Optoelectronic recording tape or strip comprising photoconductive la	365/106	396/661; 428/689;		Kuehr
13	<input type="checkbox"/>	<input checked="" type="checkbox"/>	US 4745360 A	19880517	10	Electron-beam probe system utilizing test device having interdig	324/751	250/310; 250/492.2;		Reime
14	<input type="checkbox"/>	<input checked="" type="checkbox"/>	US 5560543 A	19961001	24	Heat-resistant broad-bandwidth liquid droplet generators	239/102.2	239/135; 310/331;		Smith
15	<input type="checkbox"/>	<input checked="" type="checkbox"/>	US 4845512 A	19890704	7	Drop deflection device and method for drop marking systems	347/77	239/690		Arwa
16	<input type="checkbox"/>	<input checked="" type="checkbox"/>	US 4735364 A	19880405	10	Electrostatic spray head	239/690.1	239/691; 239/708		March
17	<input type="checkbox"/>	<input checked="" type="checkbox"/>	US 4579279 A	19860401	7	Electrostatic sprayers	239/3	239/703		March
18	<input type="checkbox"/>	<input checked="" type="checkbox"/>	US 4555712 A	19851126	12	Ink drop velocity control system	347/7	347/89; 73/861		Arwa
19	<input type="checkbox"/>	<input checked="" type="checkbox"/>	US 5903004 A	19990511	9	Energy dispersive X-ray analyzer	250/310	250/397; 250/399;		Koshi
20	<input type="checkbox"/>	<input checked="" type="checkbox"/>	US 4520264 A	19850528	10	Electron microscope	250/311	250/396ML; 250/398		Tsunc
21	<input type="checkbox"/>	<input checked="" type="checkbox"/>	US 5519216 A	19960521	11	Electron-optical imaging system having controllable elements	250/311	250/307		Bennc
22	<input type="checkbox"/>	<input checked="" type="checkbox"/>	US 5412209 A	19950502	29	Electron beam apparatus	250/310	250/396ML		Otaka
23	<input type="checkbox"/>	<input checked="" type="checkbox"/>	US 6569319 B2	20030527	41	UV light intensity detector in a water treatment system	210/85	210/192; 250/474.1;		Kuenr